

Notice of References Cited

Application/Control No.

10/585,204

Applicant(s)/Patent Under
Reexamination
KOINUMA ET AL.

Examiner

Sanza L. McClendon

Art Unit

1796

Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-5,505,985	04-1996	Nakamura et al.	427/66
*	B	US-7,608,371	10-2009	Ueno et al.	430/20
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	M	US-			

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NON-PATENT DOCUMENTS

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	U	Tsui et al. Thin Film formation of poly (N-vinylcarbazole) by laser ablation deposition. Journal of Applied Physics, vol. 85, NO. 8, 15 April 1999. pp 4189-4195
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	X	Luo et al. Deposition of oriented polymer films for liquid crystal alignment by pulsed laser ablation. Applied Surface Science, 108 (1997) pp 89-93.

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.